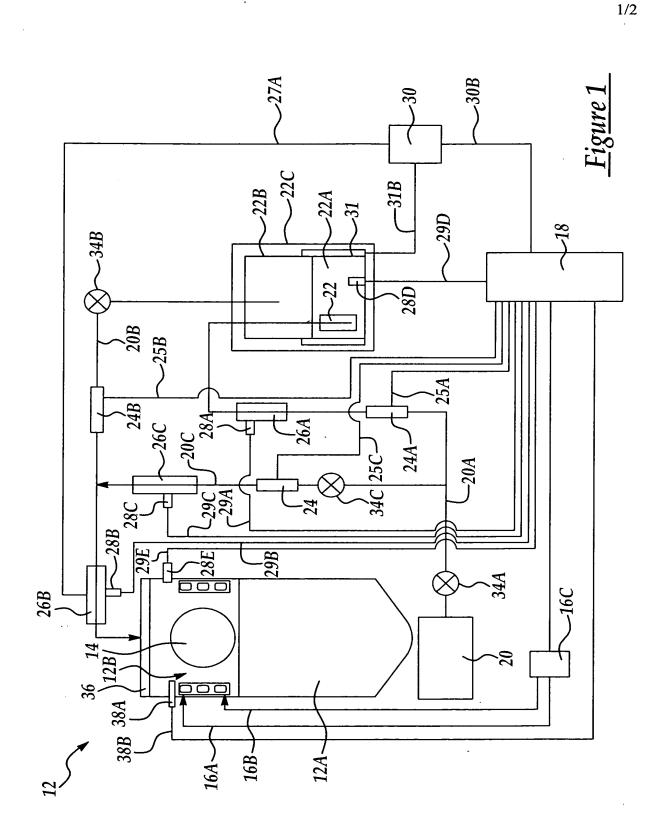
Inventor: Jia-Ren Chen Serial No.: To Be Assigned Filed: Herewith

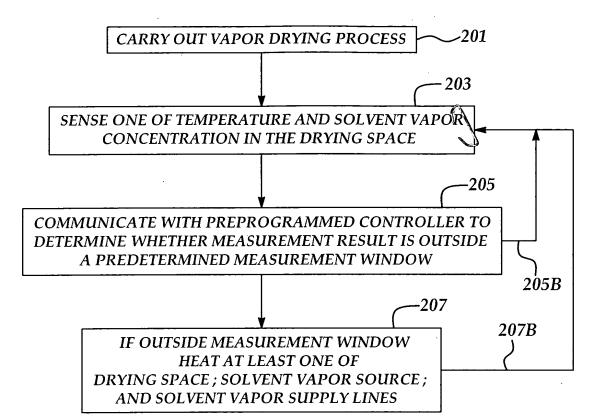
For: Method to Improve Post Wafer Etch Cleaning Process

Attorney Doc. No.: 67,200-1121



Serial No.: To Be Assigned Filed: Herewith For: Method to Improve Post Wafer Etch Cleaning Process

Attorney Doc. No.: 67,200-1121



<u>Figure 2</u>

2/2